WEST Search History

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DATE: Monday, April 25, 2005

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		DB=PGPB,USPT,USOC,EPAB,JPAB,DWPI,TDBD; PLUR=YES; OP=ADJ	
☐	L19	134/$.ccls. and (bellows accumulator)	1
☐	L18	L17 and (elevated pressure)	13
☐	L17	L15 and cleaning	408
☐	L16	L15 and (dense gas)	4
☐	L15	134/$.ccls. and (bladder or bellows)	594
☐	L14	(137/565.34).ccls. and conveying	11
☐	L13	(137/565.34).ccls. and accumulator and cleaning	8
☐	L12	(137/12 or 137/896).ccls. mixing	0
☐	L11	(137/12 or 137/896).ccls. and bellows	25
☐	L10	L9 and mixing	1
☐	L9	(137/12 or 137/896).ccls. and accumulator	13
☐	L8	L3 and wafer	1
☐	L7	L3 and cleaning	4
☐	L6	L3 and (supercritical gas)	0
☐	L5	L3and and (supercritical gas)	0
☐	L4	L3and and (dense gas)	0
☐	L3	L2 and bellows	112
☐	L2	138/$.ccls. and accumulator	1255
☐	L1	138/4.ccls. and accumulator	0

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Search Results - Record(s) 1 through 4 of 4 returned.

☐ 1. Document ID: US 20050039775 A1

Using default format because multiple data bases are involved.

L16: Entry 1 of 4 File: PGPB Feb 24, 2005

PGPUB-DOCUMENT-NUMBER: 20050039775
PGPUB-FILING-TYPE: new
DOCUMENT-IDENTIFIER: US 20050039775 A1

TITLE: Process and system for cleaning surfaces of semiconductor wafers

PUBLICATION-DATE: February 24, 2005

INVENTOR-INFORMATION:

NAME	CITY	STATE	COUNTRY	RULE-47
Whitlock, Walter H.	Chapel Hill	NC	US	

US-CL-CURRENT: 134/2; 134/19, 134/25.4, 134/26, 134/31

Full | Title | Citation | Front | Review | Classification | Date | Reference | Sequences | Attachments | Claims | KWIC | Draw D

☐ 2. Document ID: US 20040003831 A1

L16: Entry 2 of 4 File: PGPB Jan 8, 2004

PGPUB-DOCUMENT-NUMBER: 20040003831
PGPUB-FILING-TYPE: new
DOCUMENT-IDENTIFIER: US 20040003831 A1

TITLE: Supercritical fluid cleaning process for precision surfaces

PUBLICATION-DATE: January 8, 2004

INVENTOR-INFORMATION:

NAME	CITY	STATE	COUNTRY	RULE-47
Mount, David J.	North Andover	MA	US	

US-CL-CURRENT: 134/26; 134/30, 134/42, 134/902

ABSTRACT:

A dry process for the cleaning of precision surfaces such as of semiconductor wafers, by using process materials such as carbon dioxide and useful additives such

as cosolvents and surfactants, where the process materials are applied exclusively in gaseous and supercritical states. Soak and agitation steps are applied to the wafer, including a rapid decompression of the process chamber after a soak period at higher supercritical pressure, to mechanically weaken break up the polymers and other materials sought to be removed, combined with a supercritical fluid flush to carry away the loose debris.

☐ 3. Document ID: US 20020014257 A1

L16: Entry 3 of 4 File: PGPB Feb 7, 2002

PGPUB-DOCUMENT-NUMBER: 20020014257
PGPUB-FILING-TYPE: new
DOCUMENT-IDENTIFIER: US 20020014257 A1

TITLE: Supercritical fluid cleaning process for precision surfaces

PUBLICATION-DATE: February 7, 2002

INVENTOR-INFORMATION:

NAME	CITY	STATE	COUNTRY	RULE-47
Chandra, Mohan	Merrimack	NH	US	
Mount, David J.	North Andover	MA	US	
Costantini, Michael A.	Hudson	NH	US	
Moritz, Heiko D.	Nashua	NH	US	
Jafri, Ijaz H.	Nashua	NH	US	
Boyd, Jim	Amherst	NH	US	
Heathwaite, Rick M.	Greenfield	MA	US	

US-CL-CURRENT: 134/19; 134/30

ABSTRACT:

A dry process for the cleaning of precision surfaces such as of semiconductor wafers, by using process materials such as carbon dioxide and useful additives such as cosolvents and surfactants, where the process materials are applied exclusively in gaseous and supercritical states. Soak and agitation steps are applied to the wafer, including a rapid decompression of the process chamber after a soak period at higher supercritical pressure, to mechanically weaken break up the polymers and other materials sought to be removed, combined with a supercritical fluid flush to carry away the loose debris.

Full | Title | Citation | Front | Review | Classification | Date | Reference | Sequences | Attachments | Claims | KWIC | Draw D

☐ 4. Document ID: US 6602349 B2

L16: Entry 4 of 4 File: USPT Aug 5, 2003

US-PAT-NO: 6602349
DOCUMENT-IDENTIFIER: US 6602349 B2

TITLE: Supercritical fluid cleaning process for precision surfaces

DATE-ISSUED: August 5, 2003

INVENTOR-INFORMATION:

NAME	CITY	STATE	ZIP CODE	COUNTRY
Chandra; Mohan	Merrimack	NH		
Mount; David J.	North Andover	MA		
Costantini; Michael A.	Hudson	NH		
Moritz; Heiko D.	Nashua	NH		
Jafri; Ijaz	Nashua	NH		
Boyd; Jim	Amherst	NH		
Heathwaite; Rick M.	Manchester	NH		

US-CL-CURRENT: 134/19; 134/30, 134/34, 134/902

ABSTRACT:

A dry process for the cleaning of precision surfaces such as of semiconductor wafers, by using process materials such as carbon dioxide and useful additives such as cosolvents and surfactants, where the process materials are applied exclusively in gaseous and supercritical states. Soak and agitation steps are applied to the wafer, including a rapid decompression of the process chamber after a soak period at higher supercritical pressure, to mechanically weaken break up the polymers and other materials sought to be removed, combined with a supercritical fluid flush to carry away the loose debris.

27 Claims, 10 Drawing figures
Exemplary Claim Number: 1
Number of Drawing Sheets: 10

Term	Documents
DENSE	195596
DENSES	430
GAS	2631249
GASES	637360
(15 AND (DENSE ADJ GAS)).PGPB,USPT,USOC,EPAB,JPAB,DWPI,TDBD.	4
(L15 AND (DENSE GAS)).PGPB,USPT,USOC,EPAB,JPAB,DWPI,TDBD.	4

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☐ 1. Document ID: US 6619318 B2

Using default format because multiple data bases are involved.

L13: Entry 1 of 8 File: USPT Sep 16, 2003

US-PAT-NO: 6619318
DOCUMENT-IDENTIFIER: US 6619318 B2

TITLE: Multiple flow rate eductive dispenser

DATE-ISSUED: September 16, 2003

INVENTOR-INFORMATION:

NAME	CITY	STATE	ZIP CODE	COUNTRY
Dalhart; Mark D.	Mason	OH		
Sand; William F.	Cincinnati	OH		

US-CL-CURRENT: 137/565.34; 137/565.22, 137/599.12, 222/571, 417/181, 417/46

Full | Title | Citation | Front | Review | Classification | Date | Reference | Claims | KWIC | Draw De

☐ 2. Document ID: US 5151175 A

L13: Entry 2 of 8 File: USPT Sep 29, 1992

US-PAT-NO: 5151175
DOCUMENT-IDENTIFIER: US 5151175 A

TITLE: System to automatically drain filter backwash water

DATE-ISSUED: September 29, 1992

INVENTOR-INFORMATION:

NAME	CITY	STATE	ZIP CODE	COUNTRY
Royal; Claude S.	Lynchburg	VA	24501	

US-CL-CURRENT: 210/108; 137/107, 137/565.34, 166/53, 210/257.1, 210/416.3, 210/418

ABSTRACT:

A system for providing filtered well water to a building includes a filter, an accumulator downstream of the filter, and an automatic backwash valve between the filter and the well. When the well pump is deactivated, the accumulator discharges

its contents back through the filter, towards the valve, which contains a shuttle that automatically diverts the backwash water to a drain line. The valve also prevents contaminants from being siphoned into the system through the drain line.

3 Claims, 3 Drawing figures
Exemplary Claim Number: 1
Number of Drawing Sheets: 3

Full | Title | Citation | Front | Review | Classification | Date | Reference | Claims | KWIC | Draw De

3. Document ID: US 4877055 A

L13: Entry 3 of 8 File: USPT Oct 31, 1989

US-PAT-NO: 4877055
DOCUMENT-IDENTIFIER: US 4877055 A

TITLE: Leakage device for the drainage of a diaphragm accumulator

DATE-ISSUED: October 31, 1989

INVENTOR-INFORMATION:

NAME	CITY	STATE	ZIP CODE	COUNTRY
Knuchel; Pierre	Germigny L'Eveque			FR
Nollez; Jacques	Paris			FR

US-CL-CURRENT: 137/565.34; 138/30, 138/40, 60/413

ABSTRACT:

The invention relates to a leakage device for the depletion of a diaphragm accumulator when the vehicle so equipped is not in use. This device determines a permanent leakage of the liquid to a low-pressure reservoir with a predetermined rate of flow. According to the embodiment of the invention shown in the attached drawing, the device comprises a rod (150) mounted in the plunger (110), and the leakage path is defined between the rod (150) and a narrowed zone (131) of an axial passage (132) located inside the plunger. Preferably, the plunger (110) comprises a bore (126) and passages (127, 134) in communication with the inlet port (104) and the outlet port (106), and a core (130) received in the bore (126), the axial passage (132) being formed in the core (130), and the rod (150) being mounted in the core (130). The invention is used for the braking of motor vehicles.

17 Claims, 6 Drawing figures
Exemplary Claim Number: 1
Number of Drawing Sheets: 4

Full | Title | Citation | Front | Review | Classification | Date | Reference | Claims | KWIC | Draw De

4. Document ID: US 3904131 A

L13: Entry 4 of 8 File: USPT Sep 9, 1975

US-PAT-NO: 3904131
DOCUMENT-IDENTIFIER: US 3904131 A

TITLE: Pressure sewer system

DATE-ISSUED: September 9, 1975

INVENTOR-INFORMATION:

NAME	CITY	STATE	ZIP CODE	COUNTRY
Farrell, Jr.; R. Paul	Schenectady	NY		
Grace; Richard C.	Carlisle	NY		
Doyle; William J.	Delanson	NY		

US-CL-CURRENT: 241/46.02; 137/565.34, 241/185.6

ABSTRACT:

A low pressure sewer system is described which employs grinder pumps for a multiplicity of sewage generating sites and which have semi-positive displacement pumping characteristics whereby substantially constant flow (in gallons per minute) output can be produced regardless of the pressure head of the sewage piping distribution main into which the pump discharges. Each grinder pump unit includes its own anti-siphoning protection as well as self-priming characteristics and further includes a redundant check valve in the discharge piping to the low pressure sewage collection main. The low pressure collection main is comprised by small diameter, flexible, non-corroding pipes that need only be buried under the frost line and can follow the contour of the terrain of the community in which the system is installed.

33 Claims, 5 Drawing figures
Exemplary Claim Number: 1
Number of Drawing Sheets: 3

Full | Title | Citation | Front | Review | Classification | Date | Reference | Claims | KWMC | Draw D

☐ 5. Document ID: US 3079948 A

L13: Entry 5 of 8 File: USOC Mar 5, 1963

US-PAT-NO: 3079948
DOCUMENT-IDENTIFIER: US 3079948 A

TITLE: Variable volume fluid distributor

DATE-ISSUED: March 5, 1963

INVENTOR-NAME: ALLEN ROBERT L

US-CL-CURRENT: 137/565.34; 137/625.11

Full | Title | Citation | Front | Review | Classification | Date | Reference | Claims | KWMC | Draw D

6. Document ID: US 2896862 A

L13: Entry 6 of 8 File: USOC Jul 28, 1959

US-PAT-NO: 2896862
DOCUMENT-IDENTIFIER: US 2896862 A

TITLE: Accumulator

DATE-ISSUED: July 28, 1959

INVENTOR-NAME: BEDE JAMES A

US-CL-CURRENT: 239/332; 137/207, 137/565.34, 137/592, 138/26, 239/124, 239/135

Full | Title | Citation | Front | Review | Classification | Date | Reference | | | Claims | KWIC | Draw. D

7. Document ID: US 2643616 A

L13: Entry 7 of 8 File: USOC Jun 30, 1953

US-PAT-NO: 2643616
DOCUMENT-IDENTIFIER: US 2643616 A

TITLE: Pressure jet apparatus

DATE-ISSUED: June 30, 1953

INVENTOR-NAME: PAXTON DEWEY M

US-CL-CURRENT: 137/209; 134/94.1, 137/565.34, 137/571, 137/581, 417/140

Full | Title | Citation | Front | Review | Classification | Date | Reference | | | Claims | KWIC | Draw. D

8. Document ID: US 2207944 A

L13: Entry 8 of 8 File: USOC Jul 16, 1940

US-PAT-NO: 2207944
DOCUMENT-IDENTIFIER: US 2207944 A

TITLE: Fluid actuated valve

DATE-ISSUED: July 16, 1940

INVENTOR-NAME: ADAMS RICHARDSON EDWARD

US-CL-CURRENT: 251/50; 137/340, 137/494, 137/565.34, 188/106P, 239/533.8, 251/63.6, 92/162R

Full | Title | Citation | Front | Review | Classification | Date | Reference | Claims | KWIC | Draw. D

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Term	Documents
"137/565.34"	465
137/565.34S	0
ACCUMULATOR	120110
ACCUMULATORS	24405
CLEANING	766294
CLEANINGS	3285
(("137/565.34".CCLS.) AND ACCUMULATOR AND CLEANING).PGPB,USPT,USOC,EPAB,JPAB,DWPI,TDBD.	8
((137/565.34).CCLS. AND ACCUMULATOR AND CLEANING).PGPB,USPT,USOC,EPAB,JPAB,DWPI,TDBD.	8

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